



F-6971

#5/Response/E.O.T.
10.9.02
C. Moore

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Seiichi HAYASHI, et al.
Serial No. : 09/852,111
Filed : May 9, 2001
For : METHOD AND APPARATUS FOR MEASURING
THIN FILM, AND THIN FILM DEPOSITION
SYSTEM
Group Art Unit : 2882
Examiner : David P. Porta

Certificate of Mailing Under 37 CFR 1.8

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to ASSISTANT COMMISSIONER FOR PATENTS, WASHINGTON, DC 20231 on September 27, 2002.

Herbert F. Ruschmann
(Name)

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RESPONSE

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

In response to the Office Action of March 27, 2002, applicants submit the following remarks.

10/07/2002 AOSMAN1 00000119 101250 09852111

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